## AMENDMENTS

**In the Claims**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1 - 23. Canceled

24 - 69. Canceled

70. (new): An apparatus for removing dry-film contaminants, comprising:

a reservoir for receiving a dry-film removal solvent and comprising a support table capable of supporting a semiconductor device;

an ultrasonic unit disposed in the reservoir; and

a pre-filter module connected to the reservoir, wherein the pre-filter module comprises at least one trap absorbing the dry-film contaminants.

71. (new): The apparatus as claimed in claim 70, further comprising an exit tubing and an entry tubing, wherein the exit tubing is connected between an exit port of the reservoir and an inlet of the pre-filter module, and the entry tubing is connected between an entry port of the reservoir and an outlet of the pre-filter module.



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72. (new): The apparatus as claimed in claim 71, further comprising at least one control valve connected to the exit tubing.

73. (new): The apparatus as claimed in claim 71, further comprising a pump connected to the entry tubing for pumping the dry-film removal solvent into the reservoir.

74. (new): The apparatus as claimed in claim 71, further comprising a bypass tubing connected between the exit tubing and the entry tubing.

75. (new): The apparatus as claimed in claim 74, further comprising a bypass control valve connected to the bypass tubing.

76. (new): The apparatus as claimed in claim 70, further comprising a heater element disposed in the reservoir for heating the dry-film removal solvent.

77. (new): An apparatus for removing dry-film contaminants, comprising:

a reservoir for receiving a dry-film removal solvent and comprising a support table capable of supporting a semiconductor device;

an ultrasonic unit disposed in the reservoir;

a heater element disposed in the reservoir for heating the dry-film removal solvent; and

a pre-filter module connected to the reservoir, forming a closed circulation loop therewith, wherein the pre-filter module comprises at least one trap absorbing the dry-film contaminants.



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78. (new): The apparatus as claimed in claim 77, further comprising an exit tubing and an entry tubing, wherein the exit tubing is connected between an exit port of the reservoir and an inlet of the pre-filter module, and the entry tubing is connected between an entry port of the reservoir and an outlet of the pre-filter module.

79. (new): The apparatus as claimed in claim 78, further comprising at least one control valve connected to the exit tubing.

80. (new): The apparatus as claimed in claim 78, further comprising a pump connected to the entry tubing for pumping the dry-film removal solvent into the reservoir.

81. (new): The apparatus as claimed in claim 78, further comprising a bypass tubing connected between the exit tubing and the entry tubing.

82. (new): The apparatus as claimed in claim 81, further comprising a bypass control valve connected to the bypass tubing.



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